



Processing of a stacked core mirror for UV applications [8837-10]

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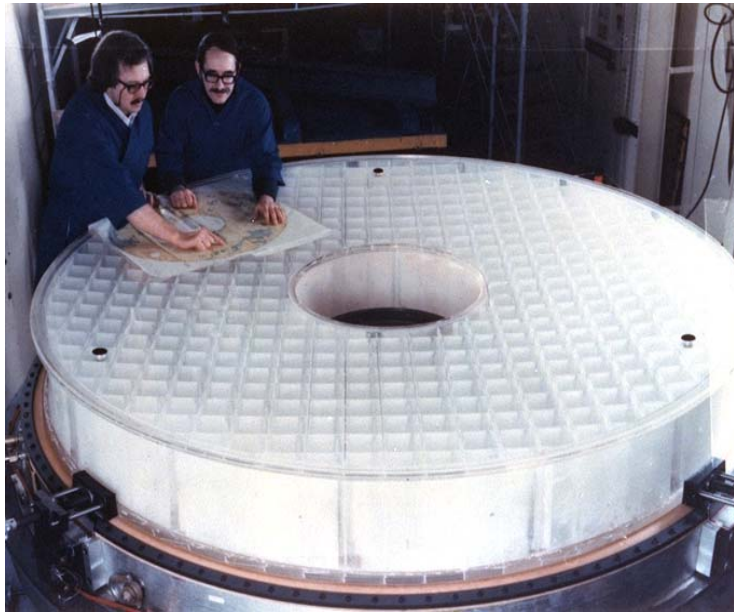
Work completed under NASA contract
number NNM12AA02C

Advanced UVOIR Mirror Technology Development (AMTD) Program

- Develop mirror blank technology applicable to building a cost effective, large (4m-8m class), passive, monolithic mirror capable of imaging in the UV spectrum
 - 0.43m demonstration mirror fabricated
 - 5.5nm RMS overall surface figure demonstrated
- Current limitations regarding a 4m class mirror
 - Significant mirror depth required to achieve stiffness
 - Core depth drives up cutting costs, schedule, risk, and areal density
 - Stack sealing of boules to achieve overall depth is very expensive and time consuming
- AMTD program addresses these issues to reduce the cost and lead time for building a 4m class mirror blank and demonstrates the ability to polish and test the blank to UV quality



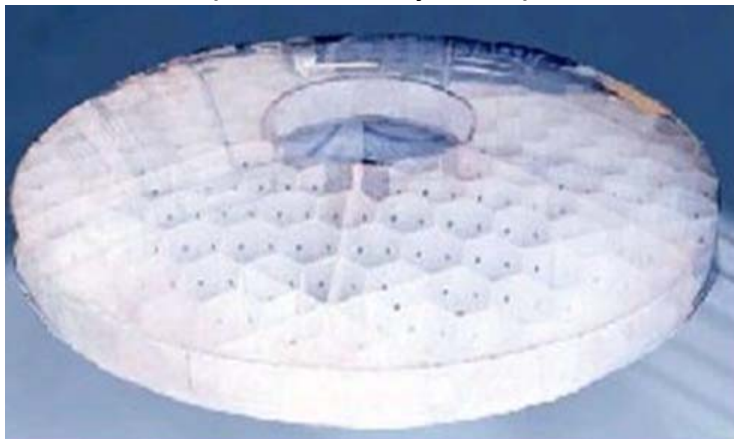
Large Lightweight ULE[®] Primary Mirrors at Exelis



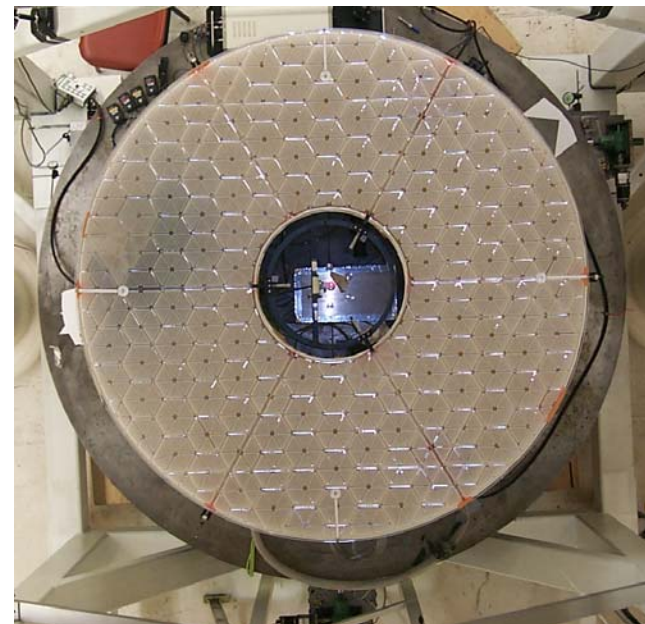
High Temperature Fusion – 1970's
(Hubble Primary Mirror)



Frit Technology with Flame Welded Core – 1980's



ATT – Waterjet Cut Core – Low Temp Fusion – 1990's

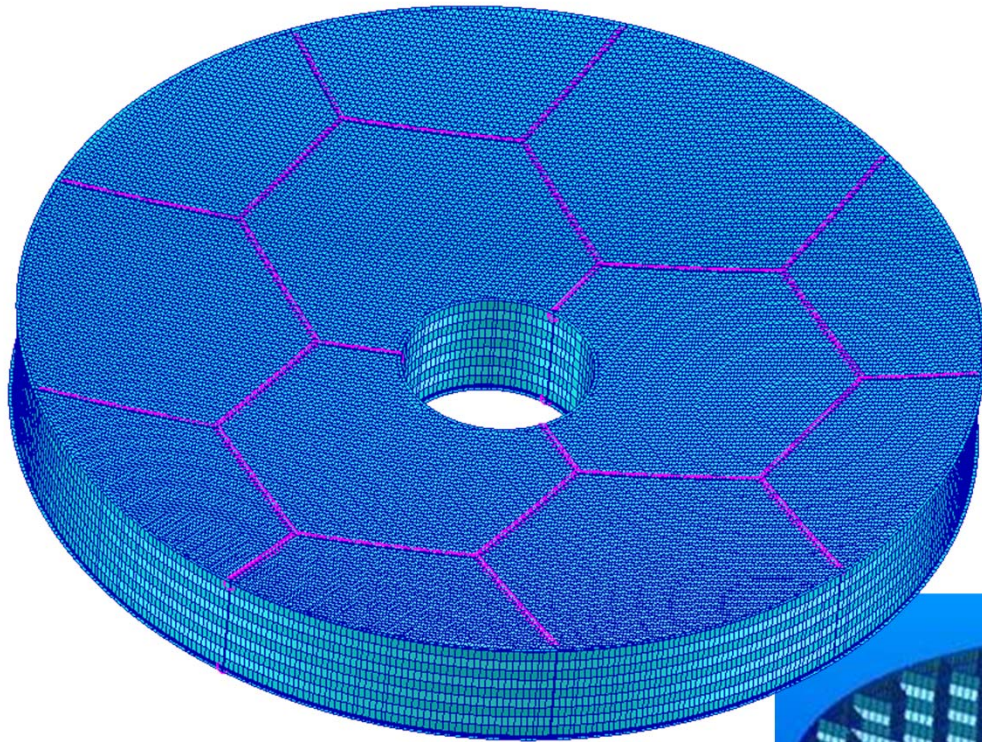


Primary Mirror – Low Temp Fusion – 2000's



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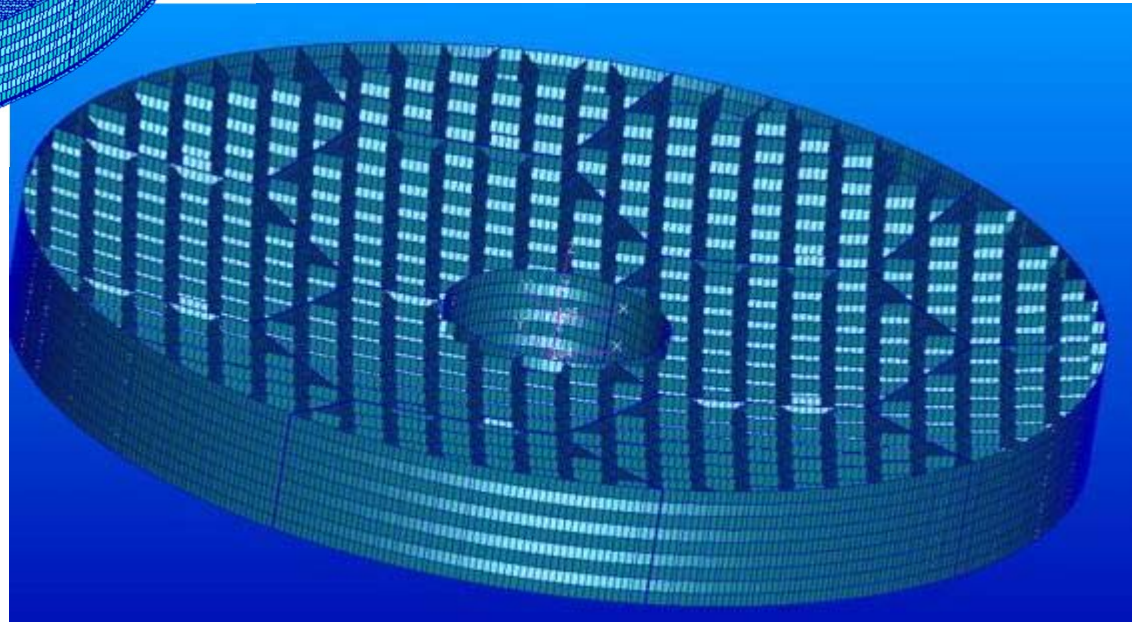
4m Mirror Concept



4m Mirror Physical Attributes

- **Pocket Milled Facesheet allows larger core cells while controlling quilting**
- **12 Core Segments**
- **3 Stacked Core Deep**
- **10m RoC (F#1.25)**

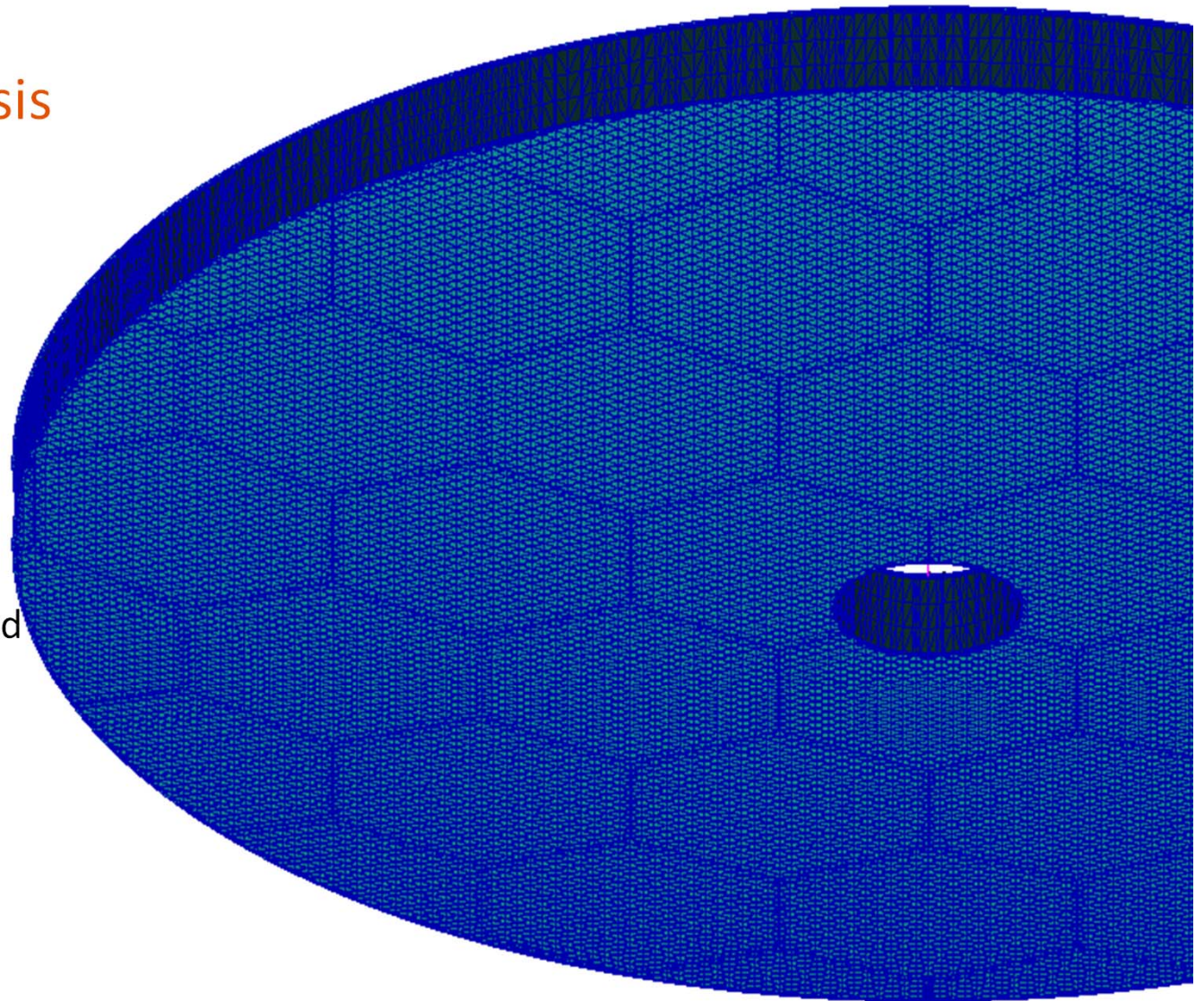
- **Fabrication risk reduced by eliminating stack sealing and deep core cutting**
- **Reduced glass needs for tooling glass**



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AMTD 8m Mirror Design and Analysis

- Stacked core and Pocket milled facesheet design
- 24.2m RoC (f#1.5)
- The 8 meter mirror modeled to assess performance
 - Model includes light-weighted face plates joined to a light-weighted core.
 - 5% additional mass added to light-weighted sections to account for corner radii.
- Total mass was 3042 kg, 60 kg/m²
- First Free-Free mode at 33 Hz

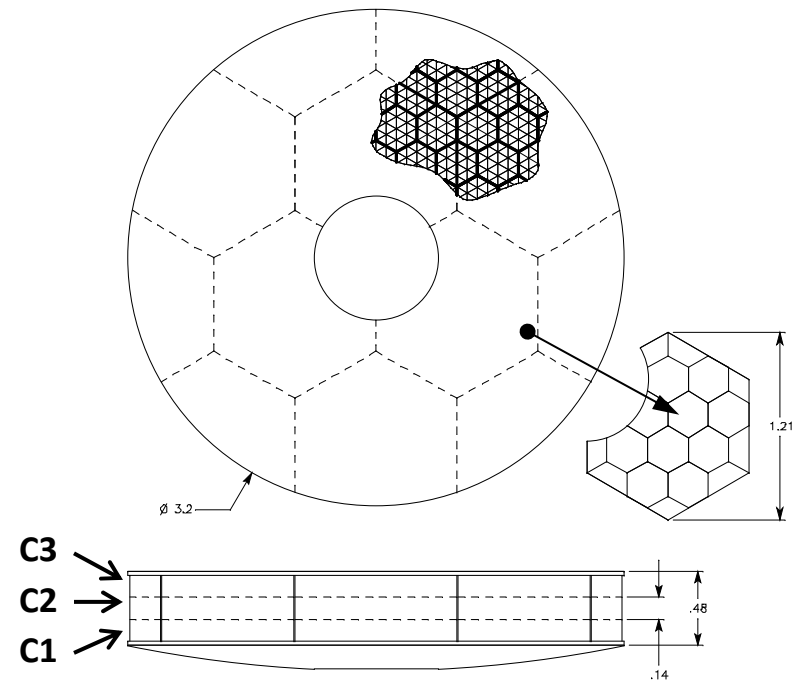
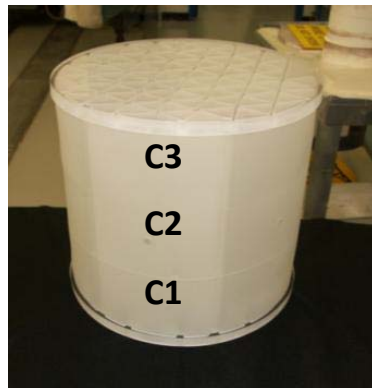


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AMTD is Developing Technologies for Near Term Large Lightweight Primary Mirrors

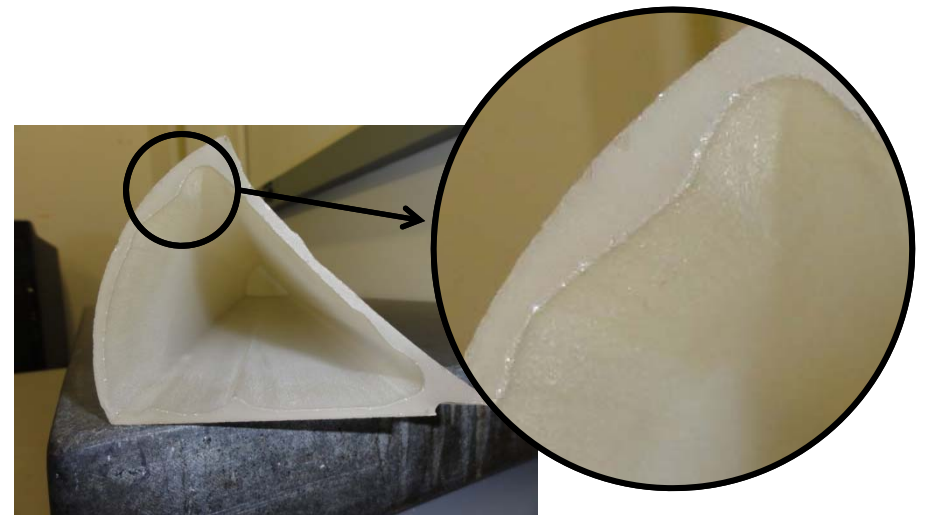
Stacked core

- > Core segments are fabricated from standard thickness boules, then stacked & fused during blank assembly to achieve a deep core
- > Eliminates need for stack sealing of boules and deep AWJ cutting of cores
- > Enables lighter weight cores and reduces cost & schedule for blank fab



Deep AWJ Cutting

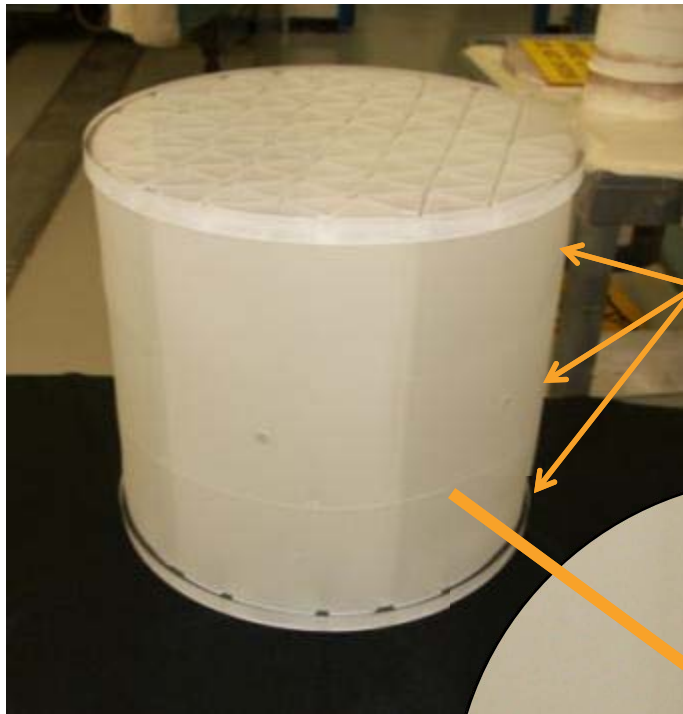
- > Extend AWJ cutting depth for LW cores from current 300mm (11.6 in) up to 480mm (19 in) depending on mirror stiffness
- > More difficult to control exit surface parameters



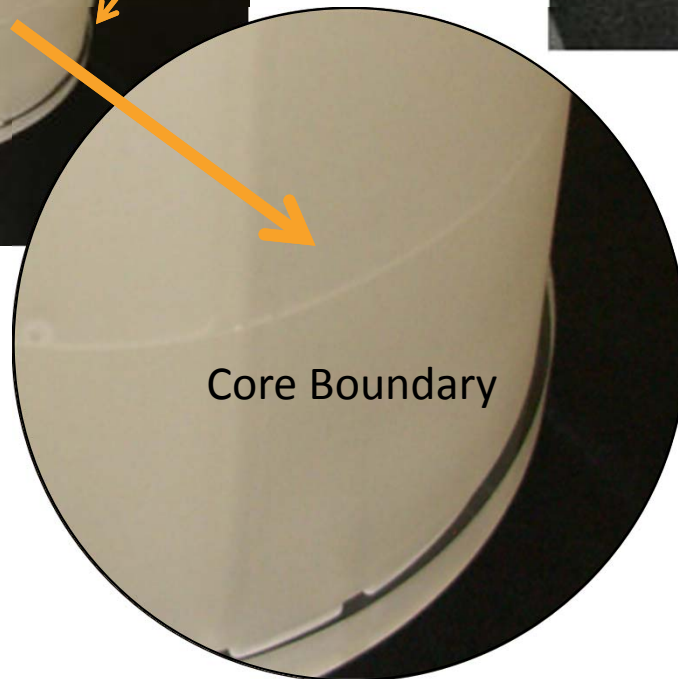
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Stacked Core Mirror Demonstration

0.4m Demonstration part fabricated



Mirror Blank
is 3 cores
high



Single Mirror Core
(Note large cell size)

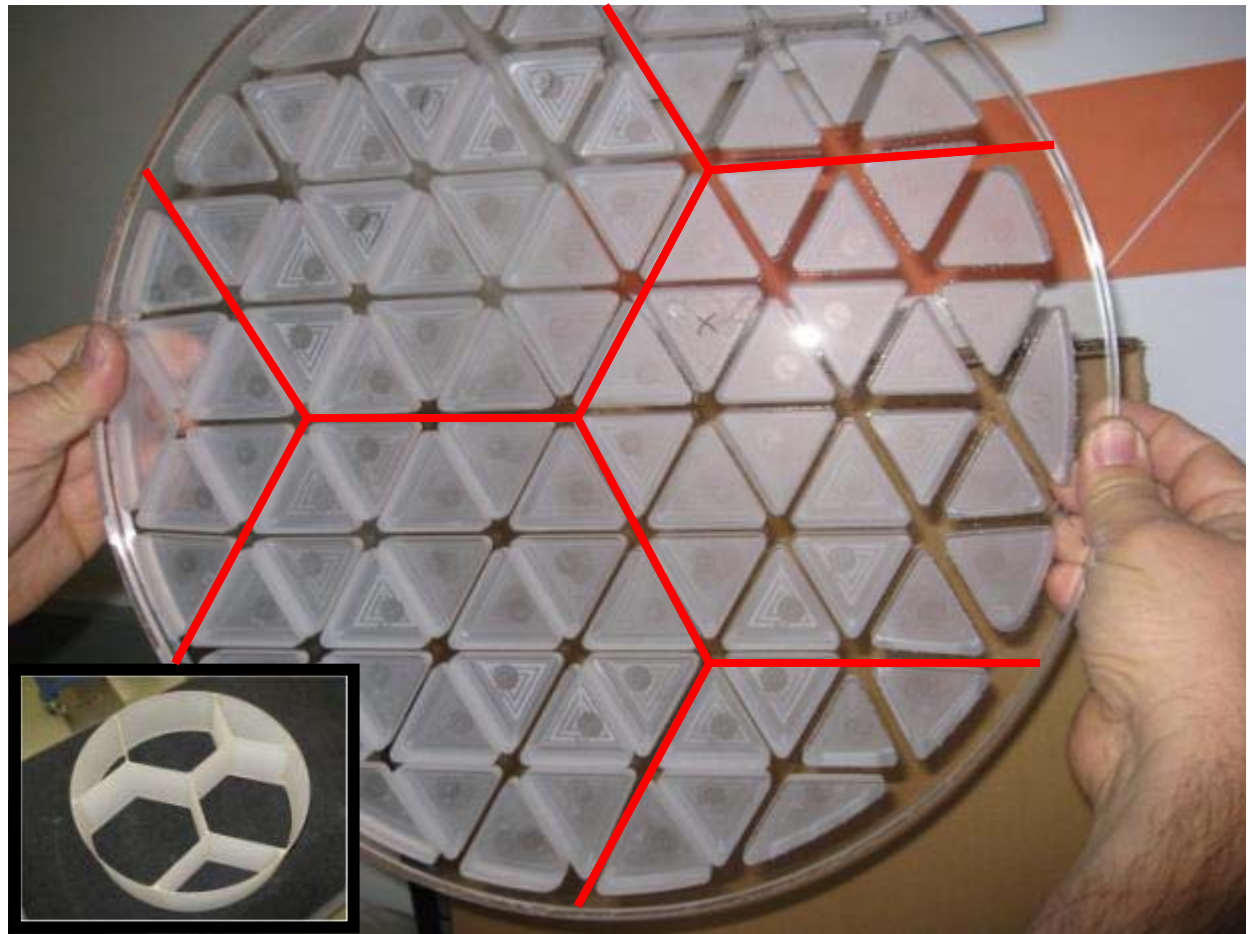
- The individual core segment surfaces are polished and AWJ just like traditional LTF mirrors
- During Low Temperature Fusion (LTF), the faceplates **and** the core segments are fused together (Co-Fired)

Faceplate Pocket Milling

- Pocket milled facesheets have been used on other mirrors to provide additional stiffness between cell supports
- Allow for much larger core cell size to reduce overall areal density
- Extended to 24 pockets to enhance UV performance



Pocket Milled Facesheet



Pocket Milled Facesheet
Core cells locations shown in red
(Core shown for reference)



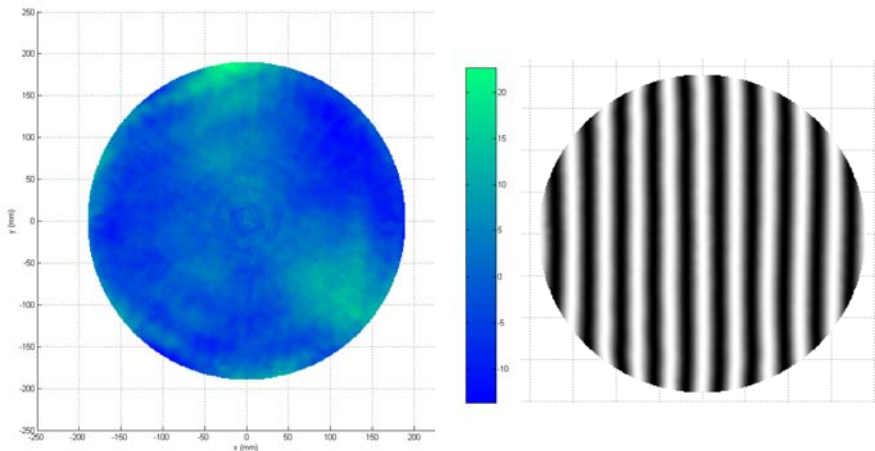
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Processing Quality

Processing completed to demonstrate that UV quality (5nm RMS) could be achieved

Multiple orientation test minimized test errors and analytical backouts

- > Some minimal trefoil did not cancel out during testing
- > Mount repeatability ultimately limited final performance



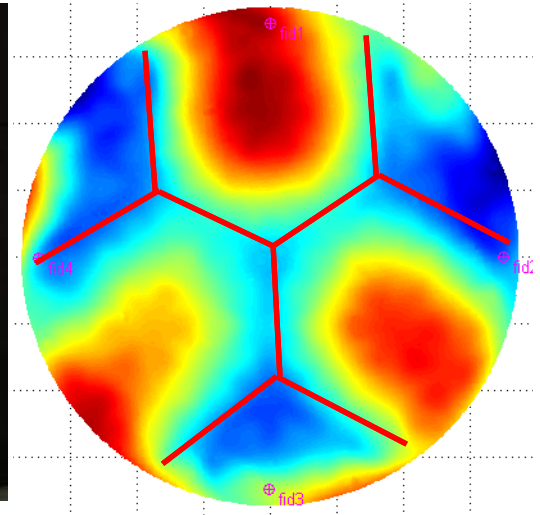
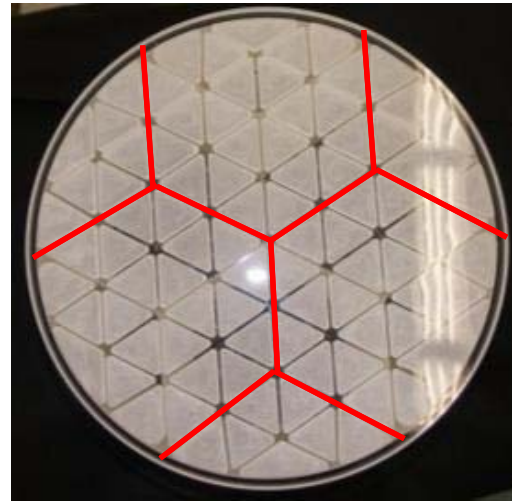
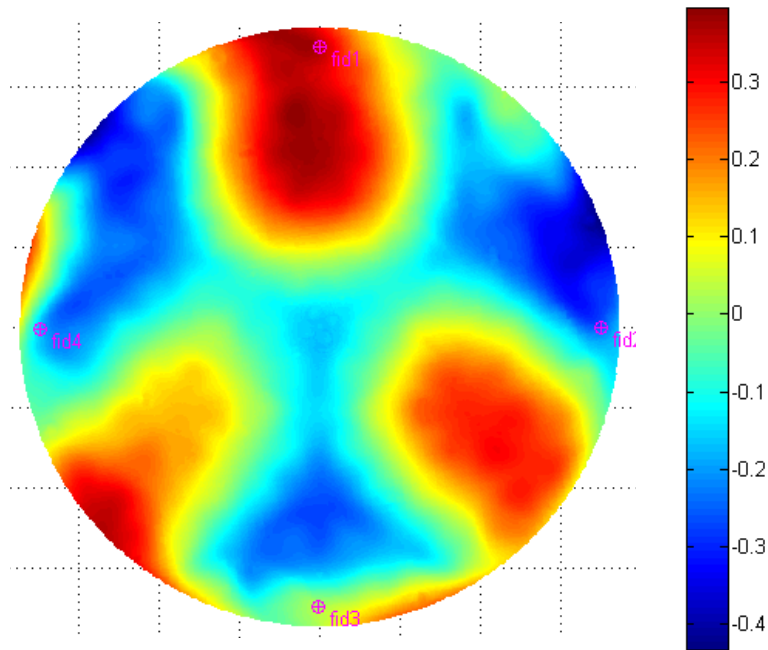
Final Optical Test – 5.5nm RMS



Demo Part in V-Block for Horizontal Testing

First Light Test

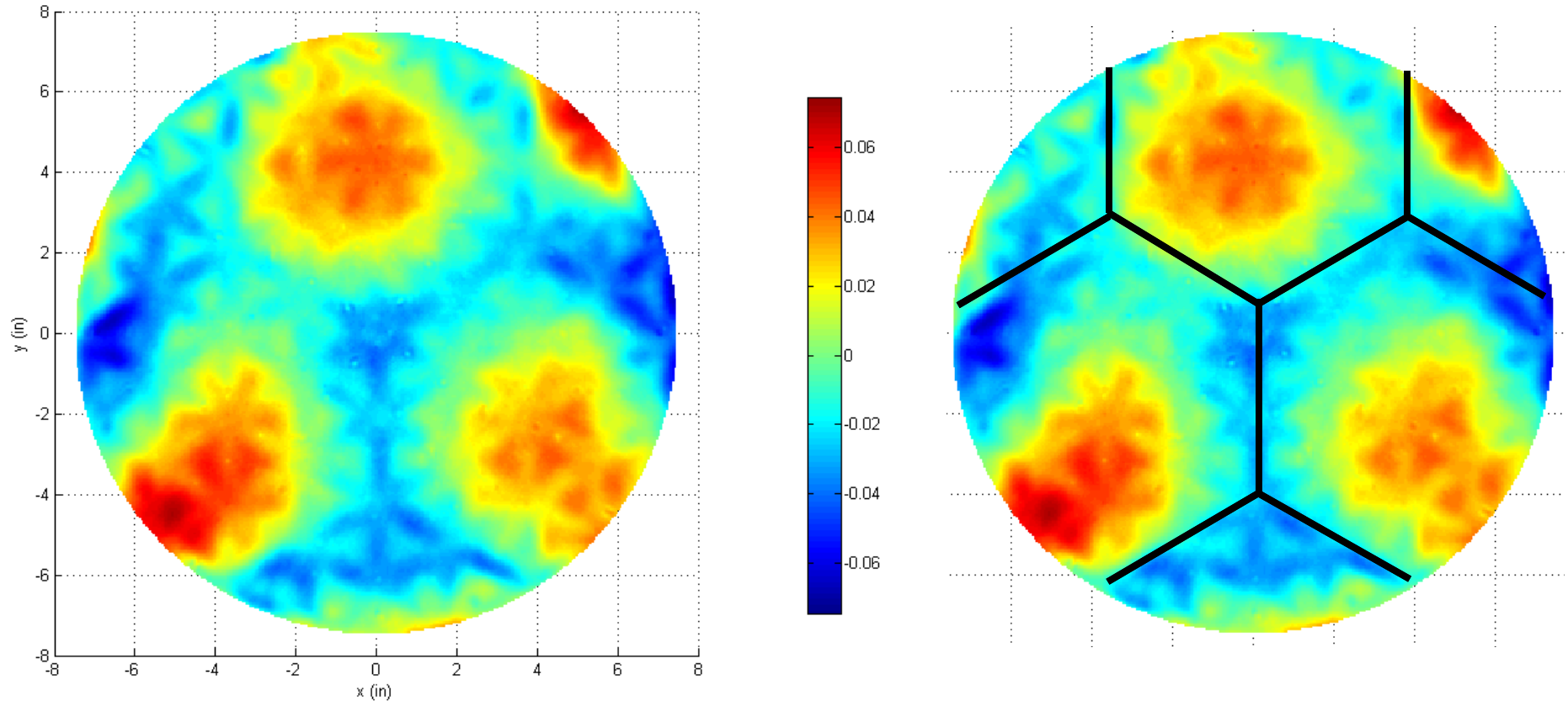
117nm RMS – 524nm P-V
Power Removed



Global polishing quilting over the large cells is observed after initial polishing

Post Ion Figuring #1

16nm RMS – 87nm P-V
Power Removed



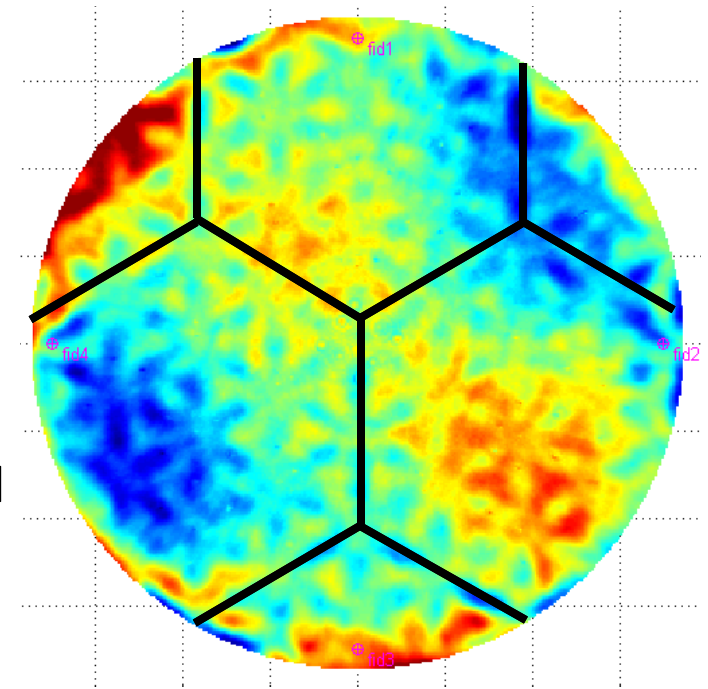
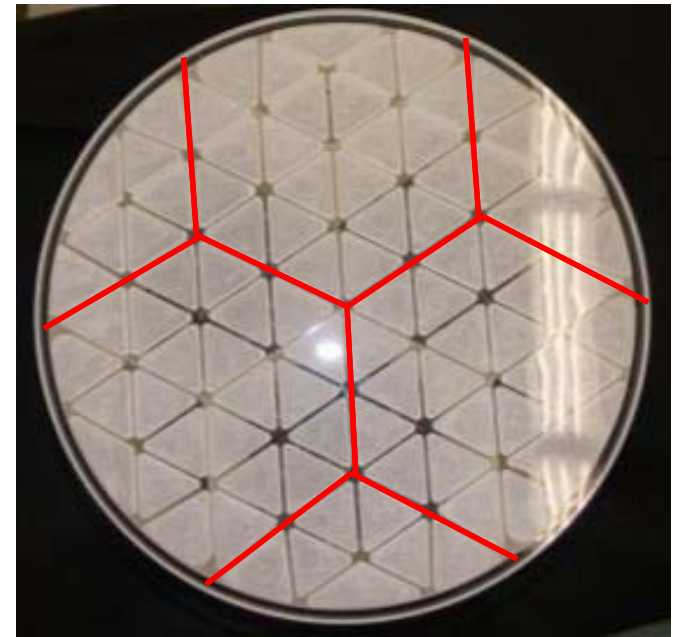
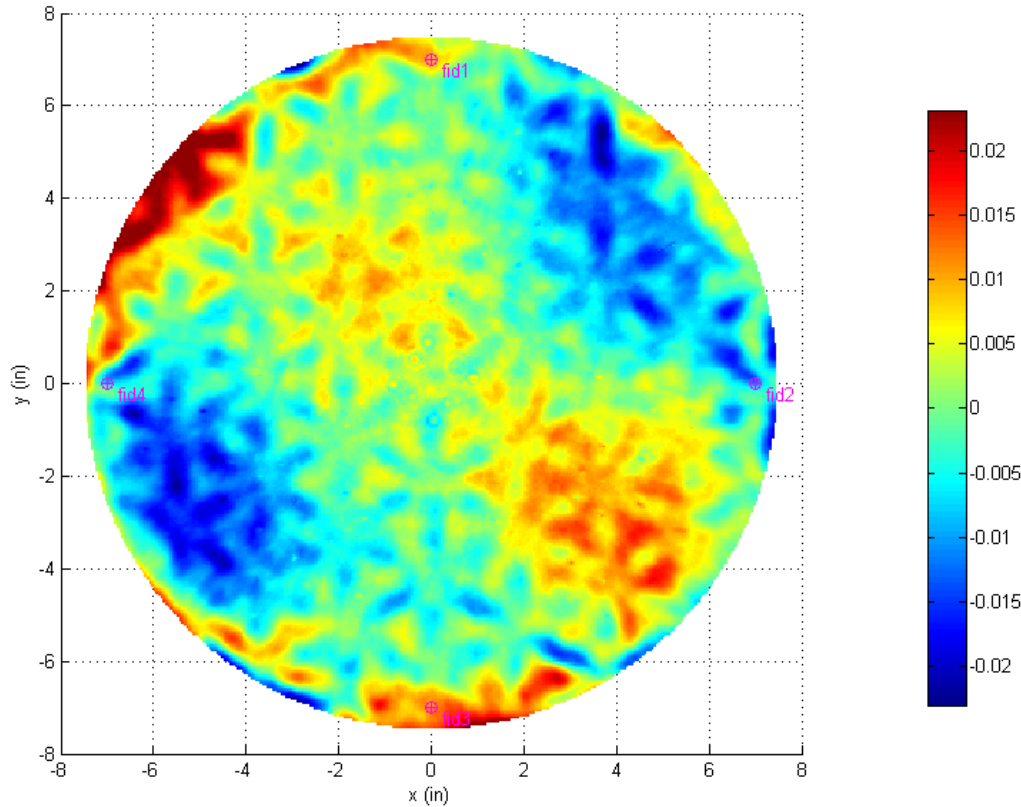
- First ion cycle greatly reduced the global figure error by 86%.
- Some cell quilting still visible



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Post Ion Figuring #2

4.9nm RMS – 37nm P-V
Power Removed



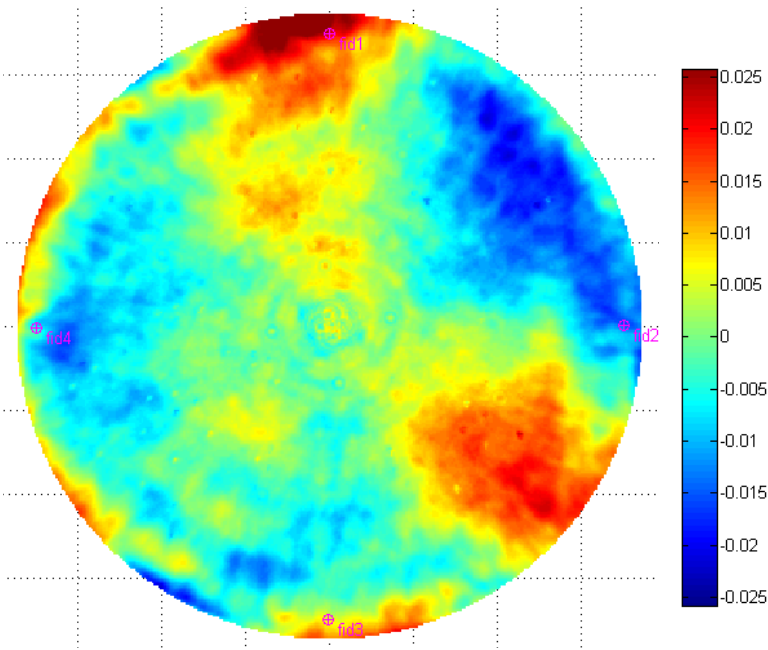
- Second ion cycle further reduced the global figure errors by an additional 68%
- Pocket milled quilting becomes visible



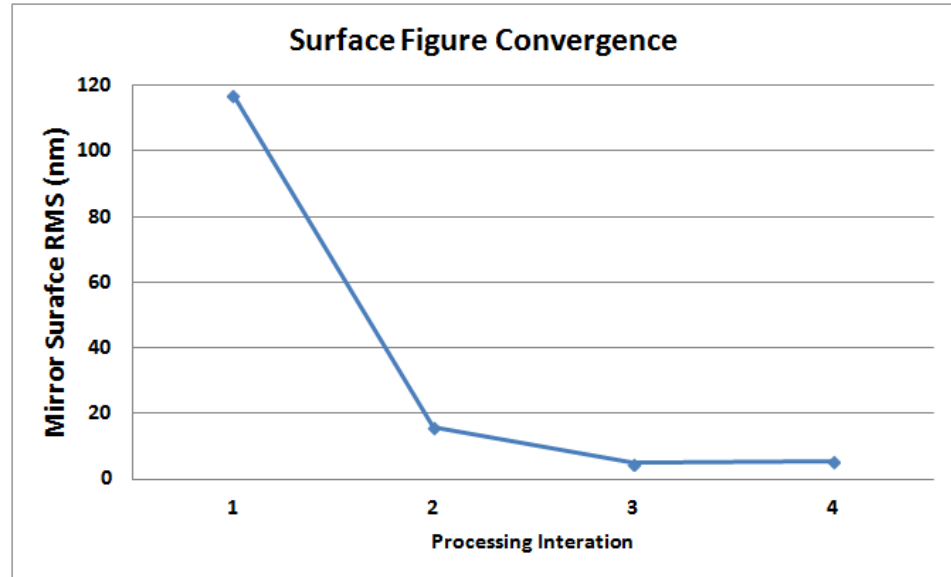
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Post Ion Figuring #3

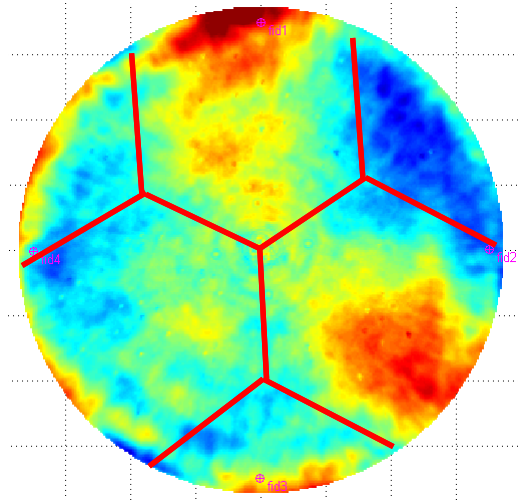
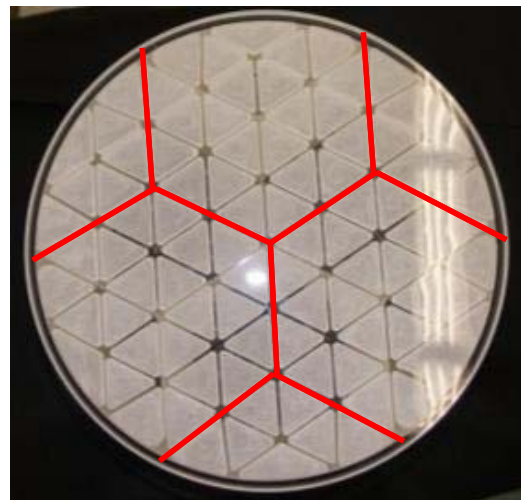
5.4nm RMS – 37nm P-V
Power Removed



- Final ion figuring run focused on pocket quilting errors
- Mount repeatability limits overall surface quality

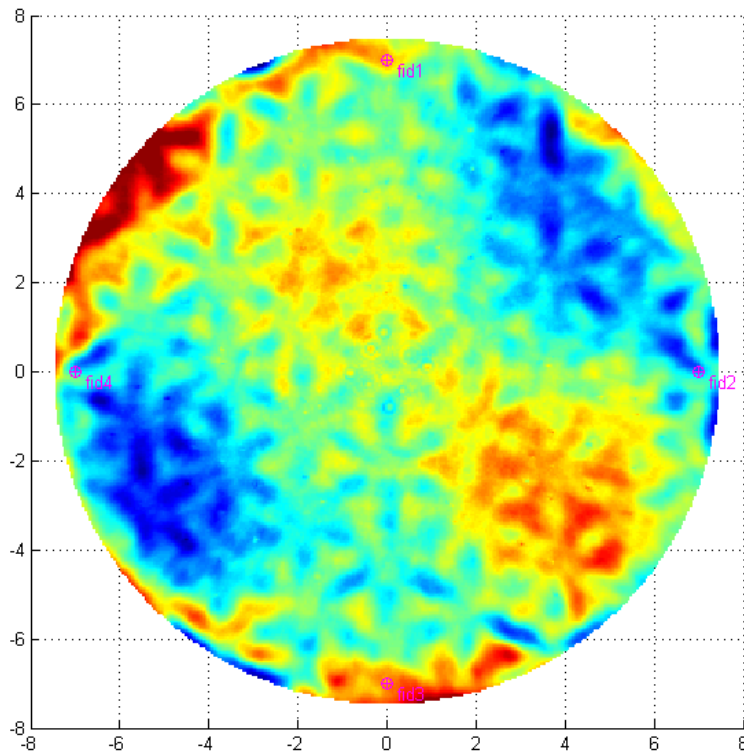


- Rapid convergence to final surface quality
- Deterministic processes reduce schedule time

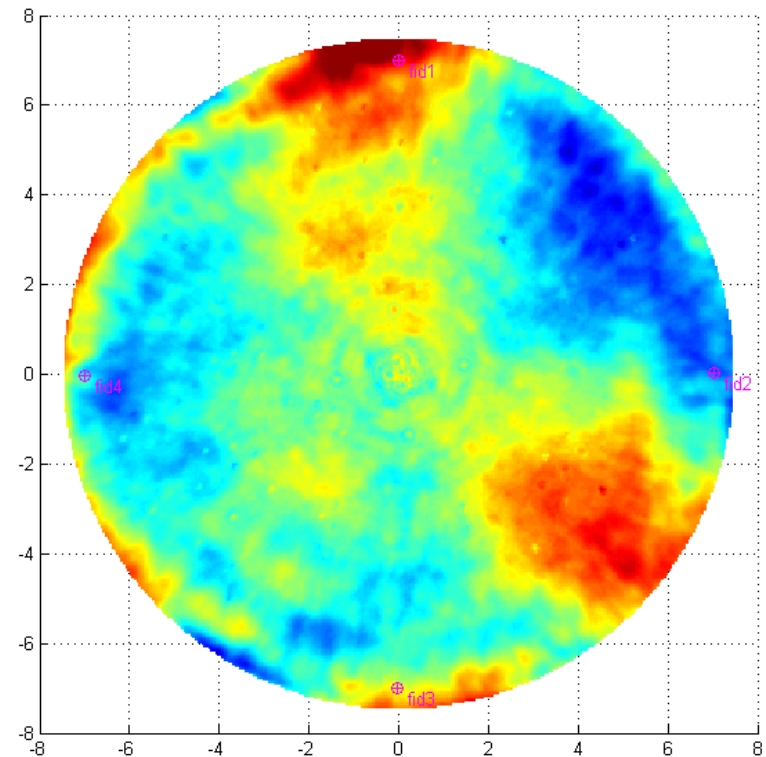


AMTD PSD Testing Summary

- Data collected using Zygo Verifire and White Light Interferometer
- Ion Figuring successfully removed most of the polishing quilting artifacts
- Results show no significant PSD change due to ion figuring in spatial periods smaller than 20mm.



Polishing Quilting



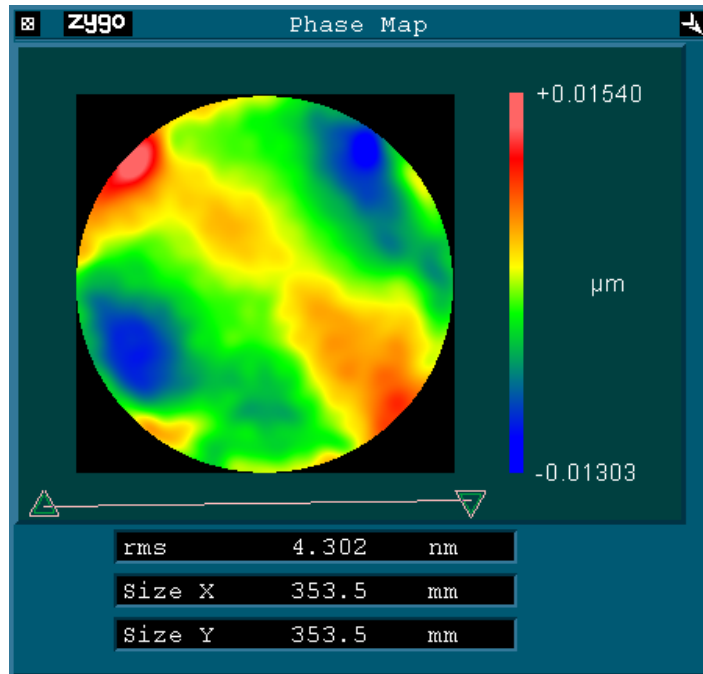
Finished



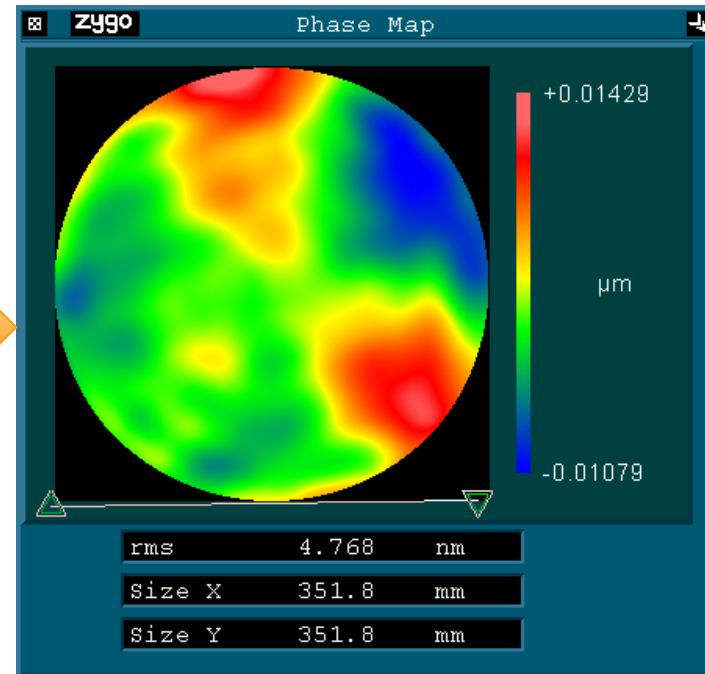
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50mm FFT Low Pass Filter (Final Ion Iteration)

Before Ion Figuring



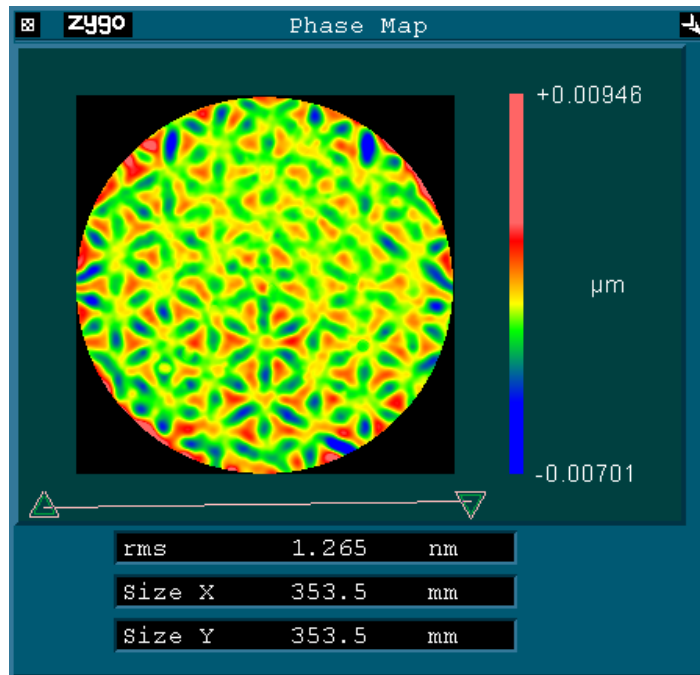
After Ion Figuring



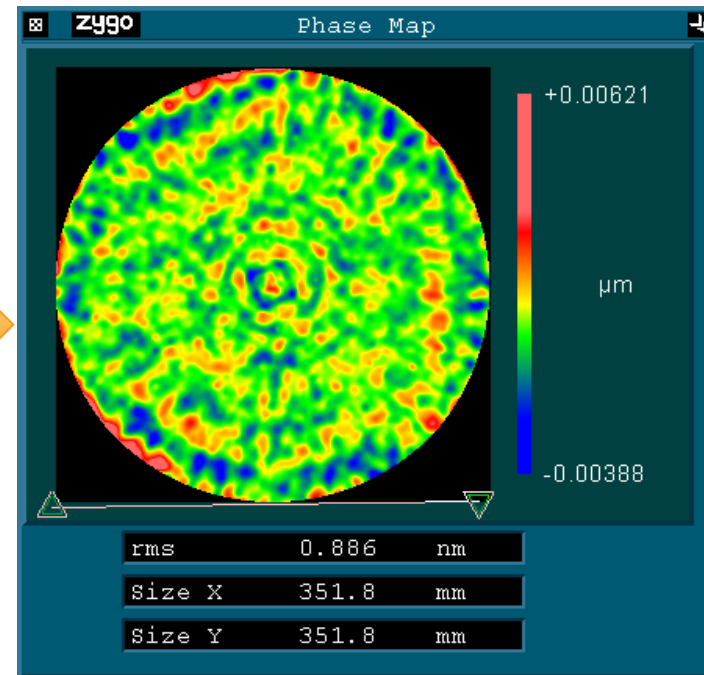
- > Low order figure error has reached the current metrology reproducibility limit in the current configuration leading to no improvement in figure errors with spatial periods longer than 50mm
- > Low order figure error present in the measurement after ion figuring is driven by mount reproducibility
- > Metrology reproducibility and accuracy could be improved with an optimized mount design and additional part rotations

50mm-10mm FFT Band Pass Filter (Final Ion Iteration)

Before Ion Figuring



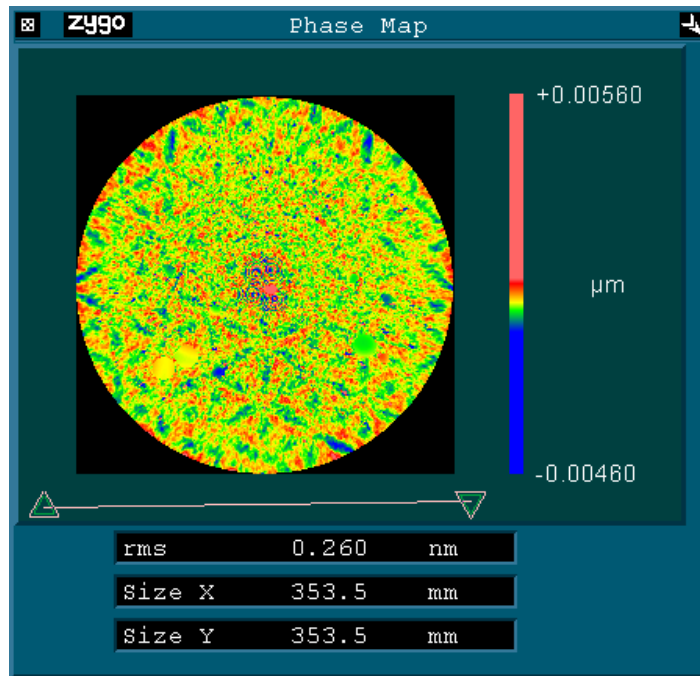
After Ion Figuring



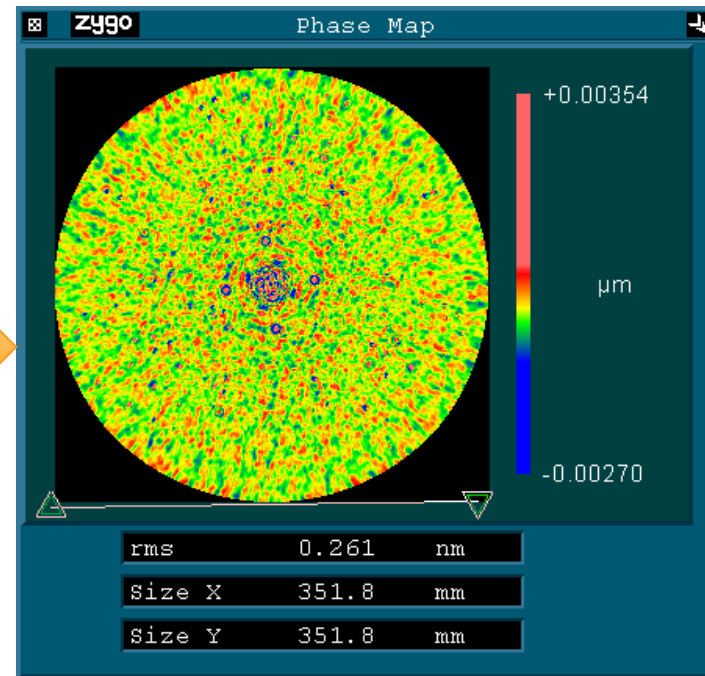
- > The quilting period appears at ~20-30mm spatial periods before final ion figuring
- > Ion figuring improved the rms in the 50-10mm spatial period band eliminating most of the quilting structure

10mm FFT High Pass Filter (Final Ion Iteration)

Before Ion Figuring

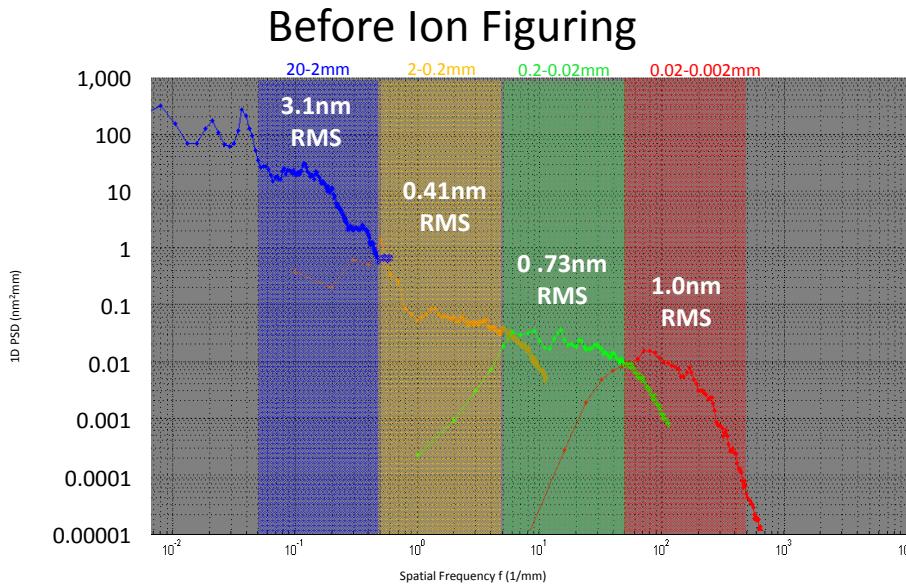


After Ion Figuring

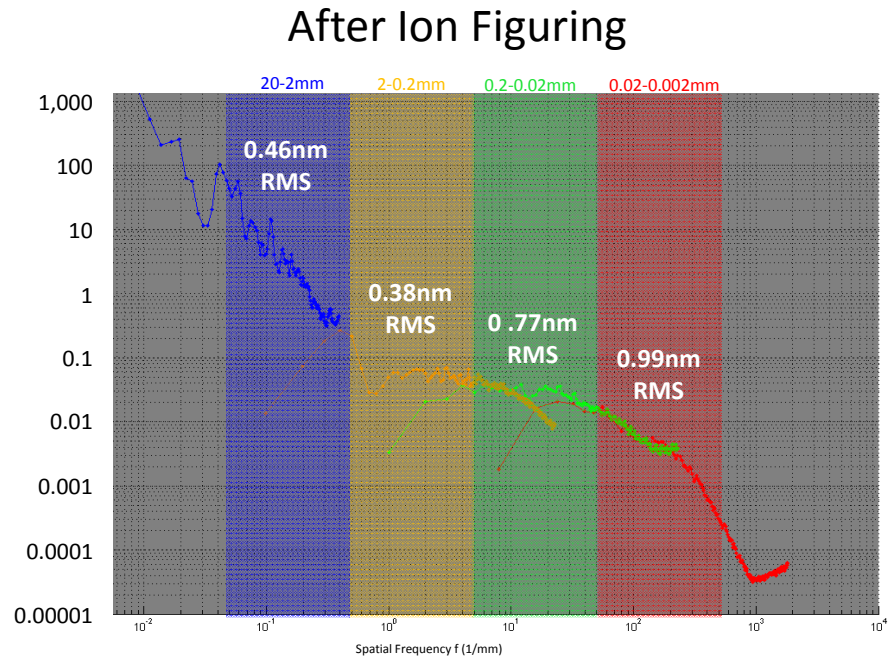


- > The shorter spatial periods, <10mm, were negligibly affected by ion figuring
- > Super polishing to improve the micro-roughness could be done if needed for the UV application

AMTD PSD Assessment (Final Ion Iteration)



- Zygo Verifire
- Full Aperature
- Zygo NewView
- 1X Objective; 0.5X relay
- 10 mm aperture; 22um pixel
- Zygo NewView
- 5X Objective; 1X relay
- 1 mm aperture; 2um pixel
- Zygo NewView
- 20X Objective; 2X relay
- 0.13mm aperture; 0.23um pixel



- > Bands were analyzed at >5X above Nyquist limit with ~5 cycles per test aperture
- > Hanning window used for PSD analysis with magnitude re-scale

> Spatial periods smaller than 20mm were negligibly affected by ion figuring as evident in the PSD plot

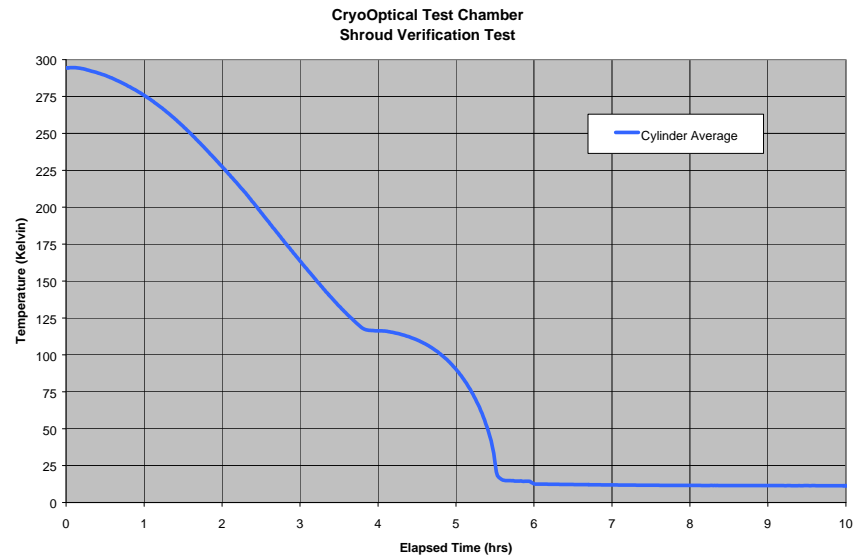
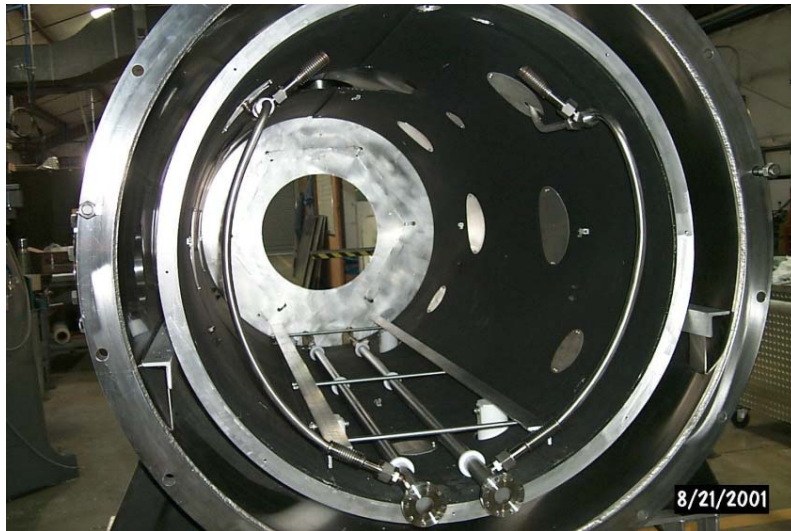


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1m x 3m Optical Test Chamber at MSFC was used for cold

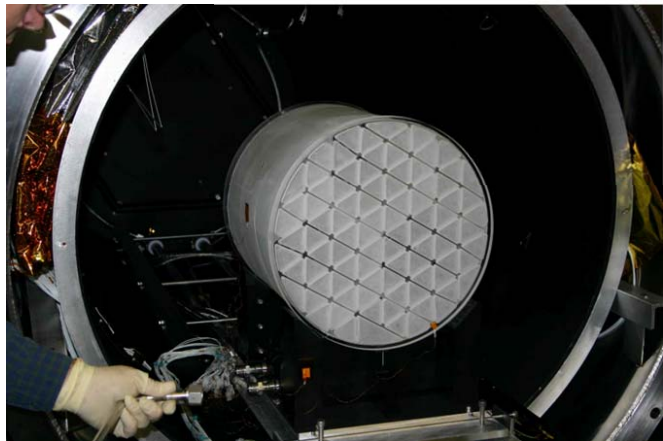
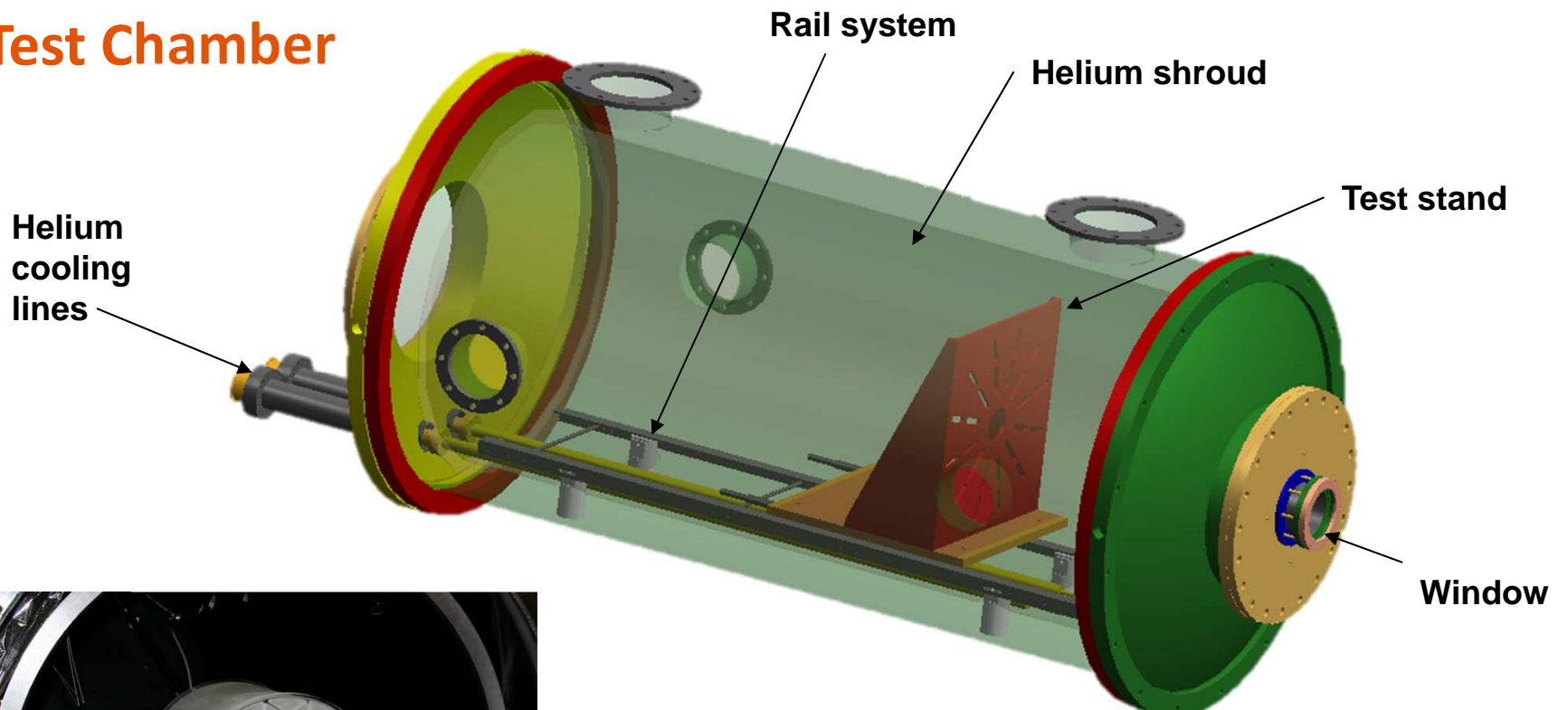


- Vacuum Chamber: 1x3 m cylinder with helium shroud.
- Optical View Ports: BK7 window; 150 mm dia. clear aperture.
- Precision stage to provide interferometer pointing and alignment.
- Operational Pressure: $< 5 \text{ E-6 Torr}$
- Temperature Range: 300 to 12K
- Typical cryo optical test: 290, 200, 100, 70, 50, 30K, 2 cycles; 3 weeks duration.

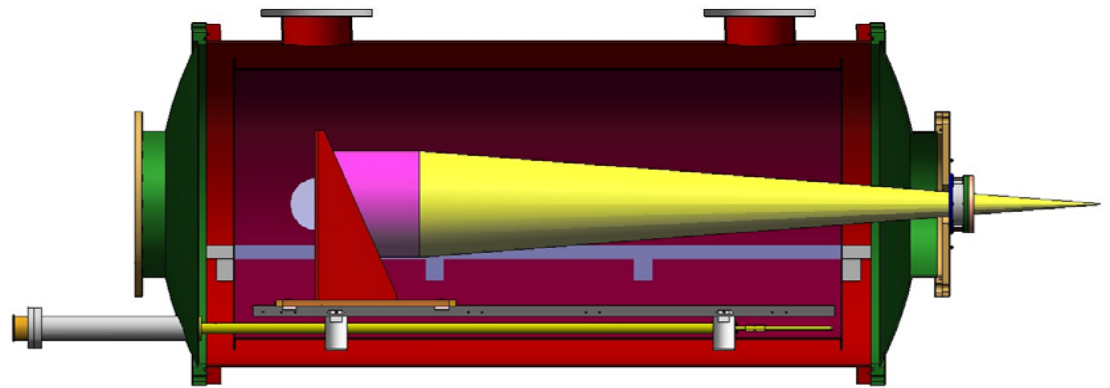


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Test Chamber



AMTD-I Mirror in the V-Block Mount inside the vacuum chamber

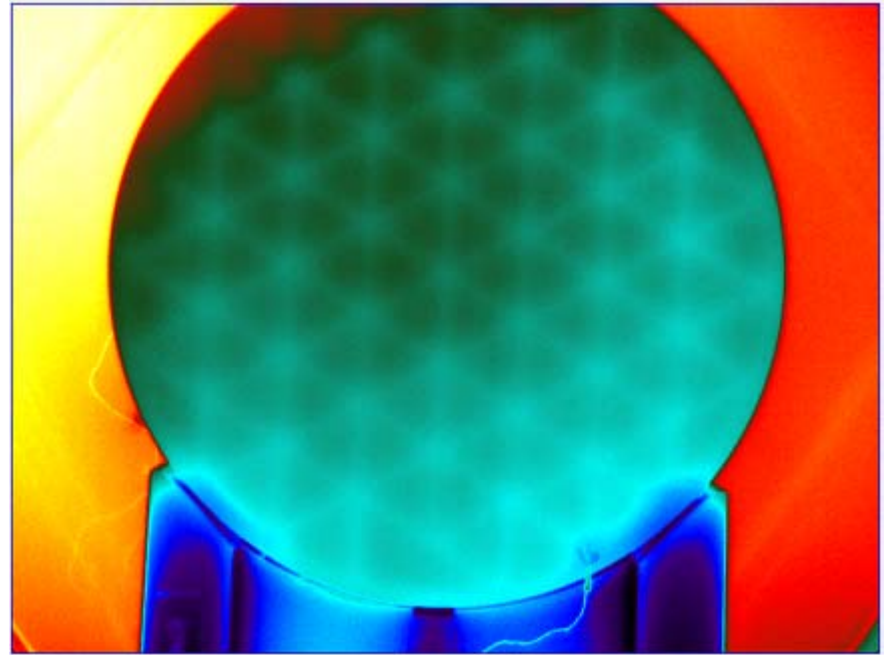
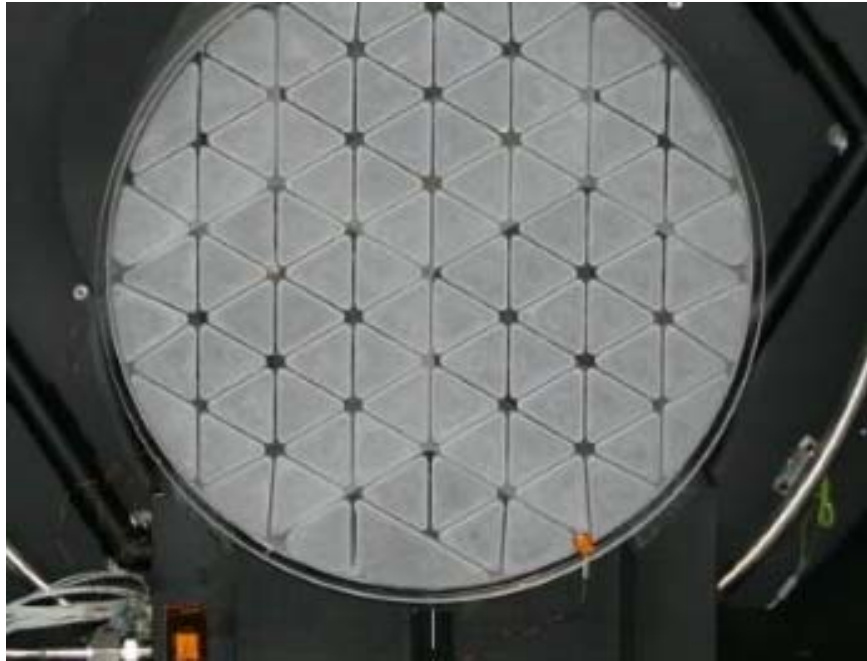


Side View of Chamber and Center of Curvature Configuration



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Thermal IR image During Temperature Transition

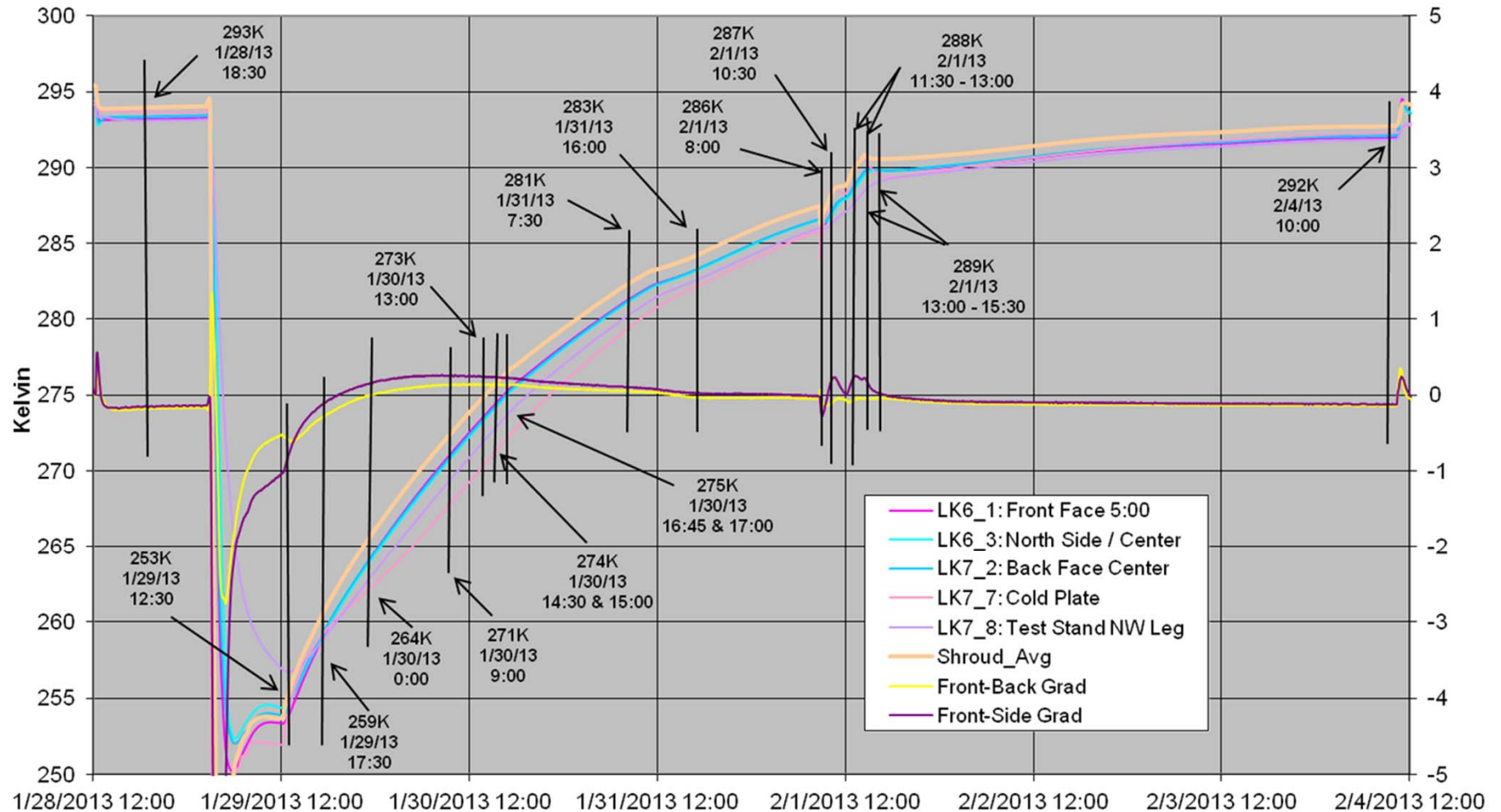


- FLIR SC655 640x480 16-bit uncooled microbolometer
- 7.5–14 μm spectral range.
- A 130mm clear aperture ZnSe window.
- IR image recorded on 1st cryo cycle @ $\sim 285\text{K}$ during warmup



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Typical Cold Cycle for Optical Testing



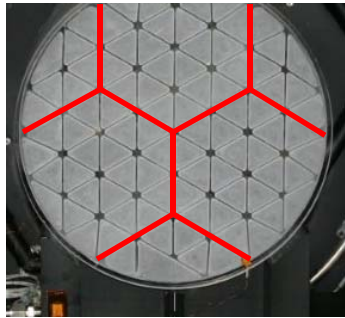
- Mirror temperature stabilize overnight for minimum gradient.
- Optical measurements at 255K, 265K, 275K, 285K and ambient.



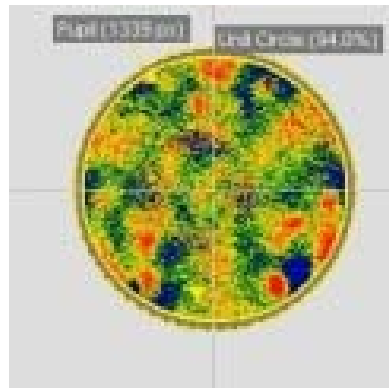
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Thermal Changes from Room Temperature

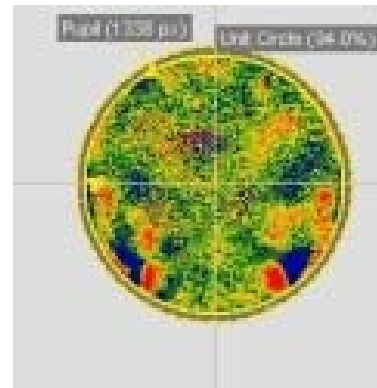
Mirror Reference Picture



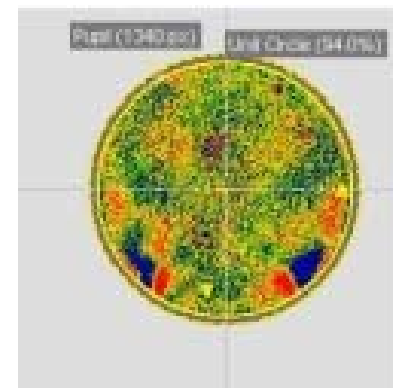
253-293K
4.0 nm rms



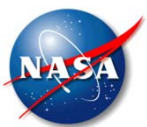
273-293K
3.7 nm rms



286-293K
3.6 nm rms



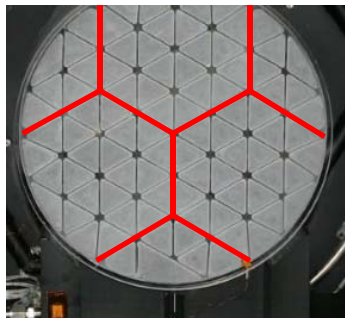
- Thermal gradients allowed to stabilize overnight
- Very small changes in surface figure were observed during thermal testing down to 253K
- Figure change was dominated by the non-kinematic V-block mount



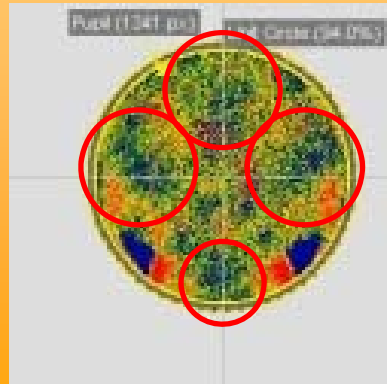
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Thermal Gradients Driven into Mirror

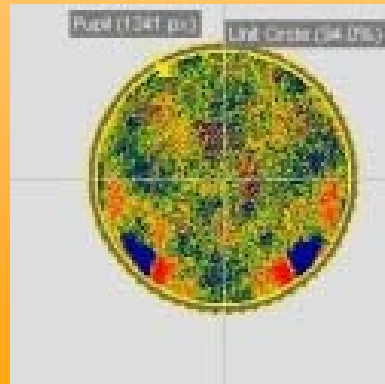
**Mirror
Reference
Picture**



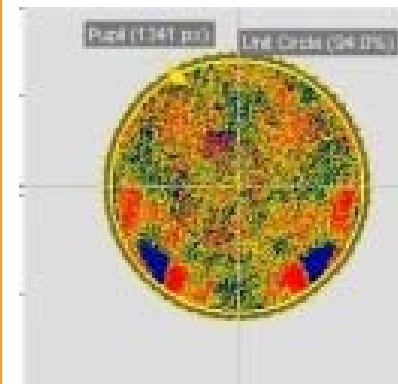
**287-293K
7.2 nm rms**



**287-293K
7.2 nm rms**



**288-293K
7.9 nm rms**

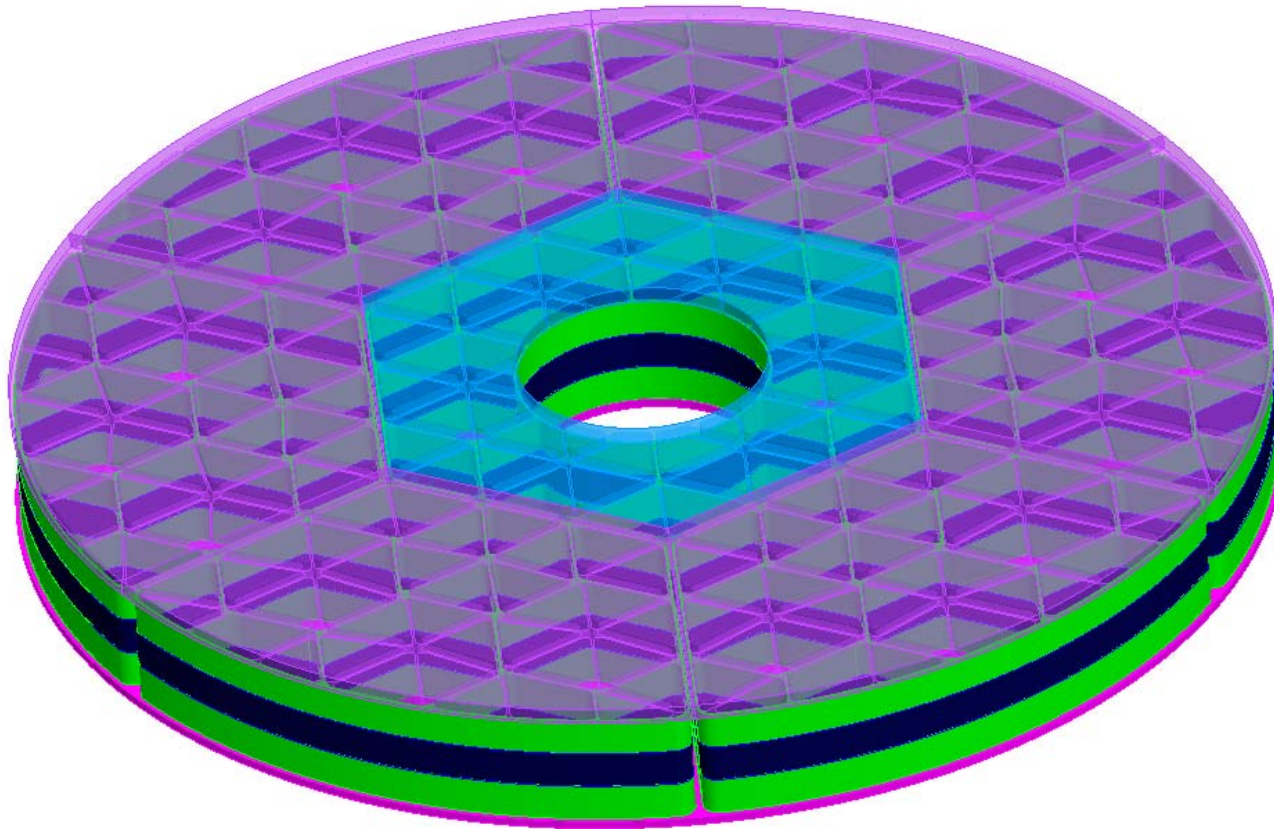


- Thermal gradients driven into mirror during temperature transitions
- Changes were larger due to gradients in the mirror structure
- Figure change was still dominated by the non-kinematic V-block mount



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1.5m, AMTD Phase II Mirror Program



- Phase II Contract awarded to the NASA/Exelis team
- Plan to build and test a 1.5m on-axis mirror using the stacked core approach
- Mirror Blank will be fabricated in 2015



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AMTD Testing Summary

- Processing of the stacked core mirror converged very quickly using ion figuring
- Results show no significant PSD change due to ion figuring in spatial periods smaller than 10mm.
- Global surface figure limited by mount repeatability
- Demonstrated that UV quality (5nm RMS) could be achieved and verified
- During cycle 3, heat was introduced after 286K measurements to induce thermal gradient, resulting in higher residual rms values for 287K and 288K.
- Minimal surface deformation seen during steady state thermal transition.
- All work performed under NASA contract number NNM12AA02C
 - COTR: Michael R. Effinger

